

# **Er<sup>3+</sup> doped monolithic 1-D dielectric microcavity fabricated by rf-sputtering for coherent emission at 1.5 $\mu$ m**

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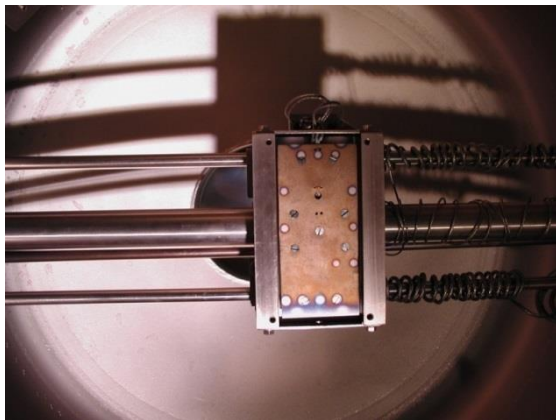
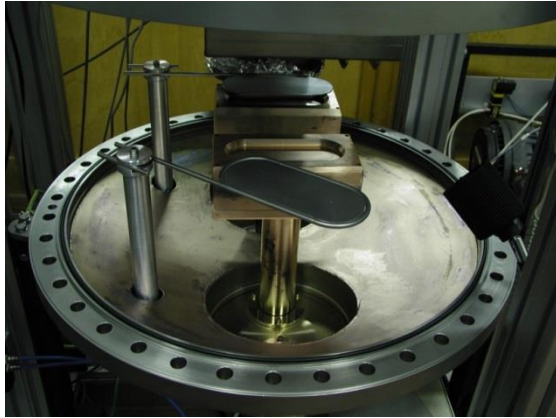
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## RF-Sputtering deposition

### Deposition apparatus

- 2 rectangular Magnetron
- 2 Power supplier + 2 automatic matching box
- Cooling close circuit dedicated to the magnetrons
- The Ar gas flow during the deposition is controlled by automatic valve
- Sample holder (10 x 6 cm) with thermometer and heater (max 100°C)
- 20 cm distance between target and substrate
- Oil-free pumping system
- Reaction chamber + Pre chamber with cleaning of the substrate (heating up to 120°C)
- PC monitor and control the main operations during the deposition process

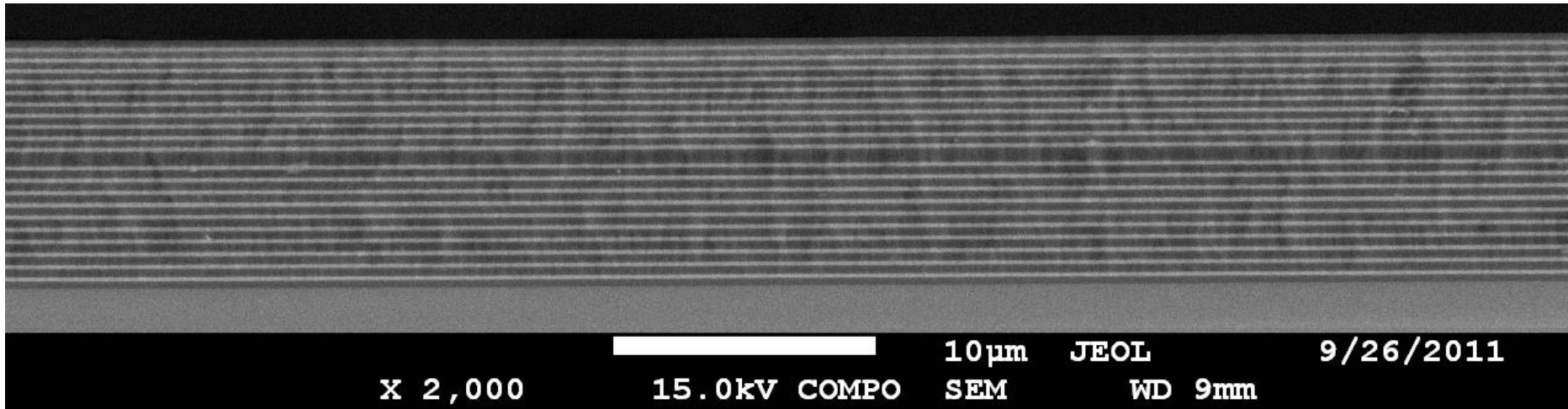
### Viable Materials

- ✓  $\text{SiO}_2$ ;  $\text{TiO}_2$ ;  $\text{HfO}_2$ ;  $\text{GeO}_2$ ;  $\text{ZrO}_2$ ;  $\text{TeO}_2$ ;  $\text{ZnO}_2$ ;  $\text{W}_2\text{O}_3$
- ✓  $\text{SiO}_2\text{-TiO}_2$ ;  $\text{SiO}_2\text{-HfO}_2$ ;  $\text{SiO}_2\text{-GeO}_2$
- ✓ Er; Yb; Dy; Eu; Ho; Nd; Sm; Tb; Tm;

### Thickness monitor

- ❖ 2 quartz microbalance faced on the 2 targets
- ❖ Calibration on  $\text{SiO}_2$  and  $\text{TiO}_2$  films of thickness of more that 1  $\mu\text{m}$  by mline apparatus
- ❖ Resolution  $\sim 1\text{\AA}$

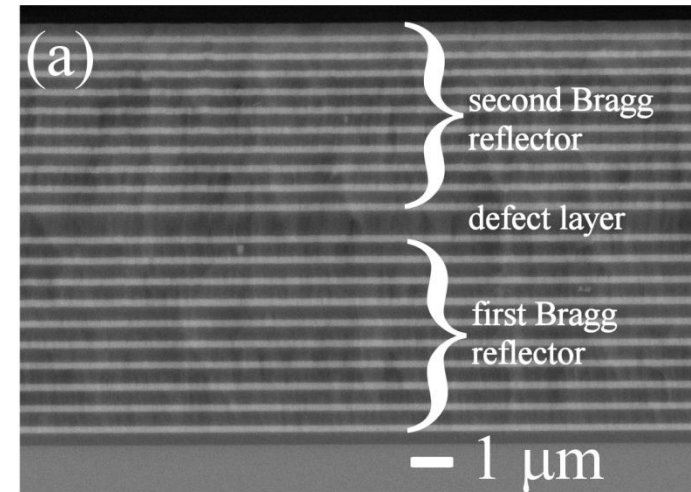
# 1-D microcavities fabricated by RF-sputtering



**Bragg Mirror:** 20 alternated quarter wave layers  $\text{TiO}_2$  (170 nm) and  $\text{SiO}_2$  (320 nm).

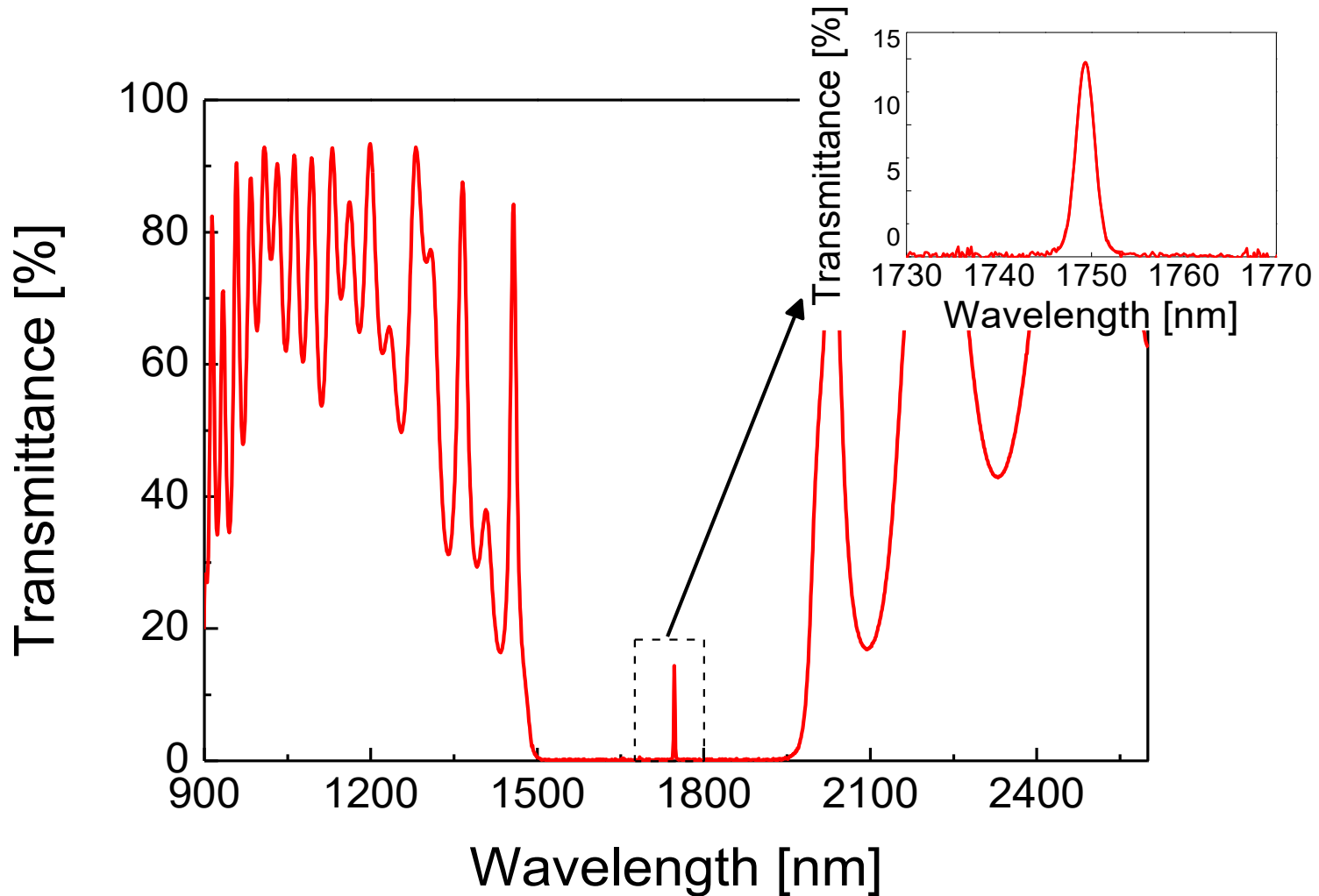
**Active layer:** half wave (640 nm)  $\text{SiO}_2$  activated with 0.2 mol % of  $\text{Er}^{3+}$ .

The dark regions corresponds to  $\text{SiO}_2$  and the white regions corresponds to  $\text{TiO}_2$



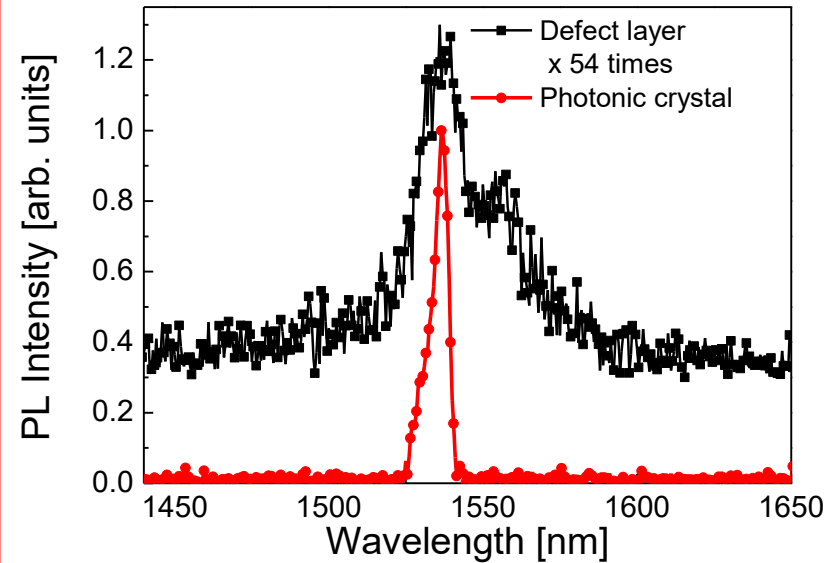
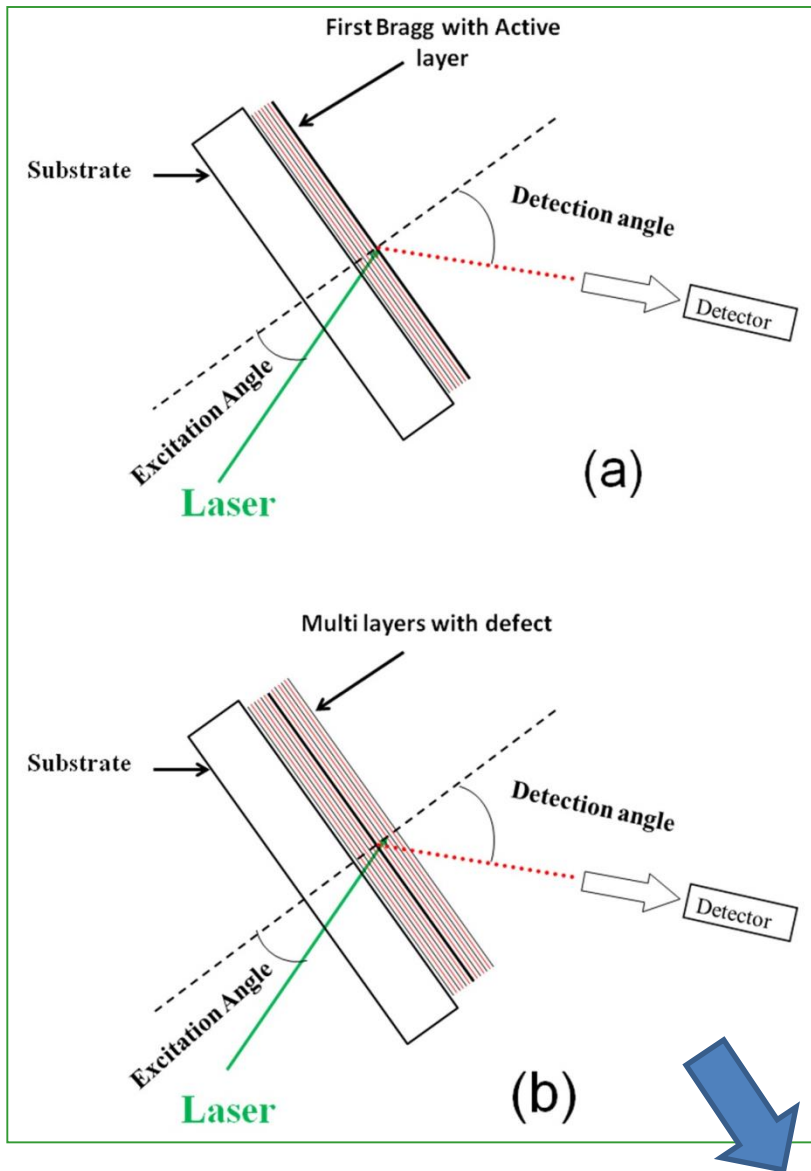
- ❖ S. Valligatla, A. Chiasera, S. Varas, N. Bazzanella, D.N. Rao, G.C. Righini, M. Ferrari, "High quality factor 1-D  $\text{Er}^{3+}$ -activated dielectric microcavity fabricated by RF-sputtering", Optics Express 20(19), 21214-21222 (2012)
- ❖ A. Chiasera, F. Scotognella, L. Criante, S. Varas, G. Della Valle, R. Ramponi, M. Ferrari, "Disorder in Photonic Structures Induced by Random Layer Thickness", Sci. Adv. Mater. 7 (2015) 1207-1212.
- ❖ S. Valligatla, A. Chiasera, S. Varas, P. Das, B.N.S. Bhaktha, A. Lukowiak, F. Scotognella, D.N. Rao, R. Ramponi, G.C. Righini, M. Ferrari, "Optical field enhanced nonlinear absorption and optical limiting properties of 1-D dielectric photonic crystal with ZnO defect", Optical Materials 50 (2015) pp. 229-233.

## Transmission measurements



Transmittance spectrum of the cavity with two Bragg reflectors. The stop band range from 1490 to 1980 nm. The cavity resonance corresponds to the sharp maximum centred at 1.749 nm. The line width of the resonance is 1.97 nm that correspond to a quality Q factor of 890.





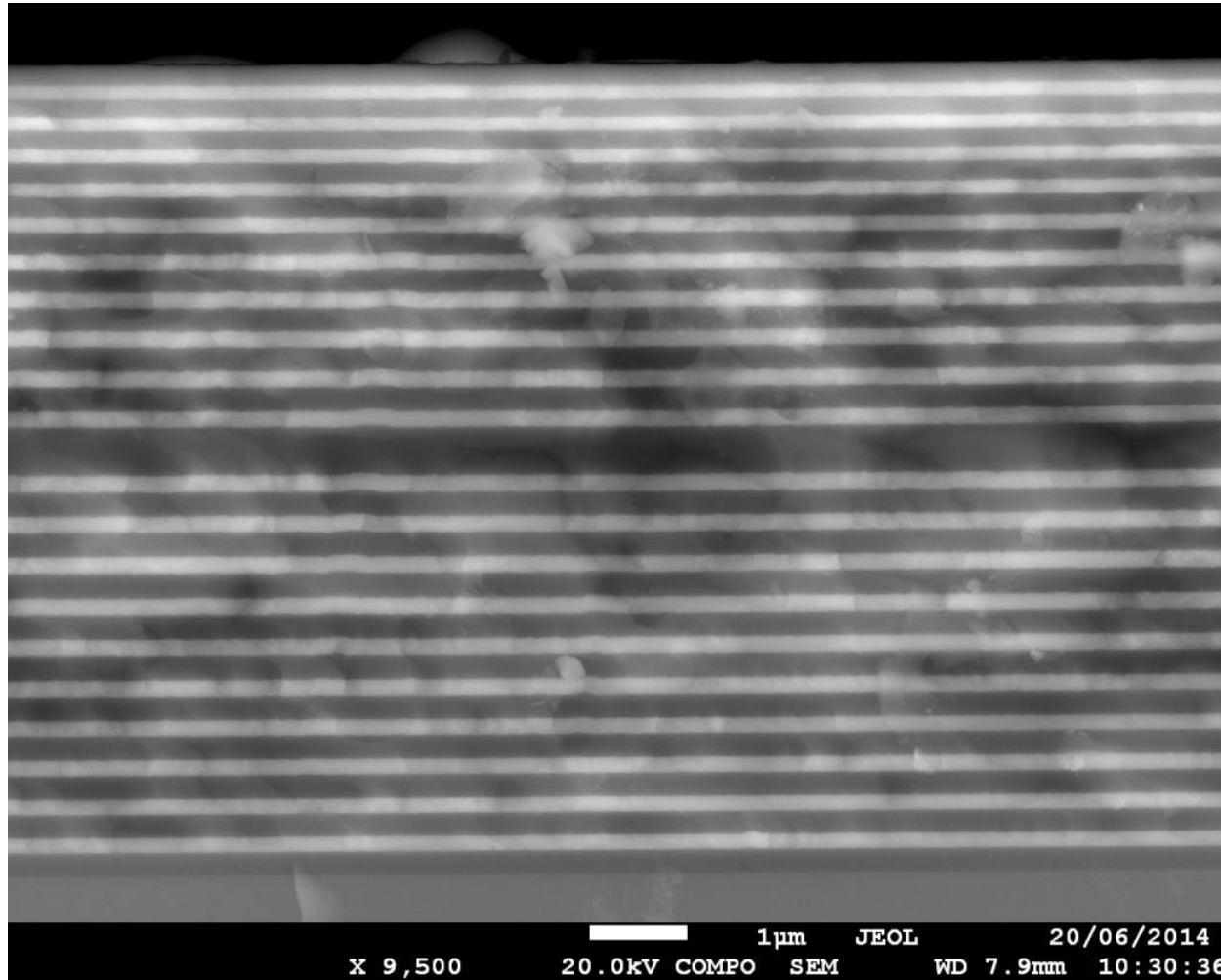
${}^4I_{13/2} \rightarrow {}^4I_{15/2}$  photoluminescence spectra of the cavity activated by  $\text{Er}^{3+}$  ion in 1-D photonic crystal and of the single  $\text{Er}^{3+}$ -doped  $\text{SiO}_2$  active layer with first Bragg mirror. The light is recorded at  $50^\circ$  from the normal on the samples upon excitation at 514.5 nm.

Schematics of the excitation and detection geometries employed for a reliable assessment of the influence of the cavity on the 1.5  $\mu\text{m}$  emission band of  $\text{Er}^{3+}$  ion.

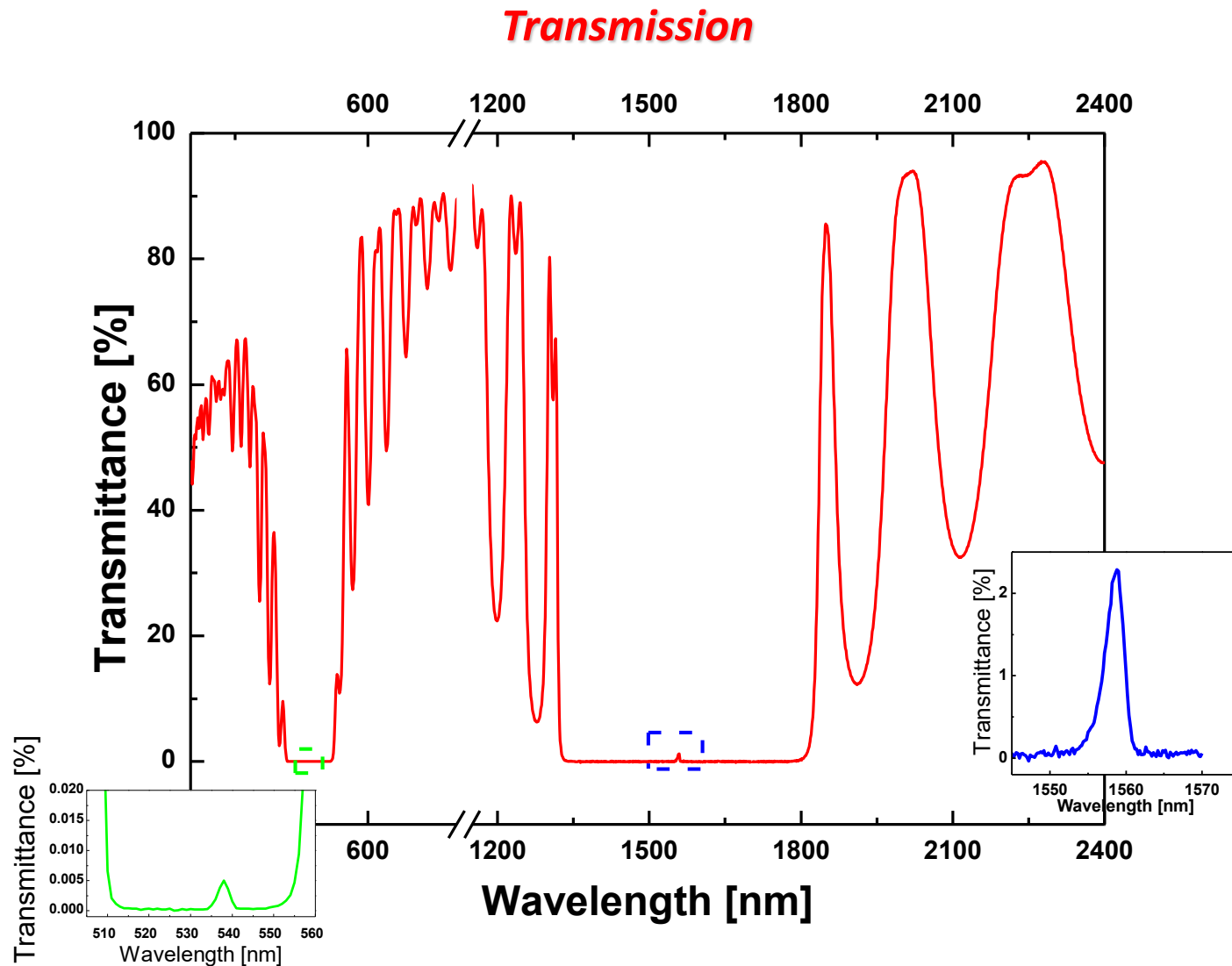
Fig. (a): configuration for the  $\text{Er}^{3+}$ -activated reference sample:  
 Fig. (b): configuration for the  $\text{Er}^{3+}$ -activated 1-D microcavity.

**Coherent emission from fully  
Er<sup>3+</sup> doped monolithic 1-D  
dielectric microcavity  
fabricated by rf-sputtering**

***Coherent emission from fully  $\text{Er}^{3+}$  doped monolithic 1-D dielectric microcavity fabricated by rf-sputtering***



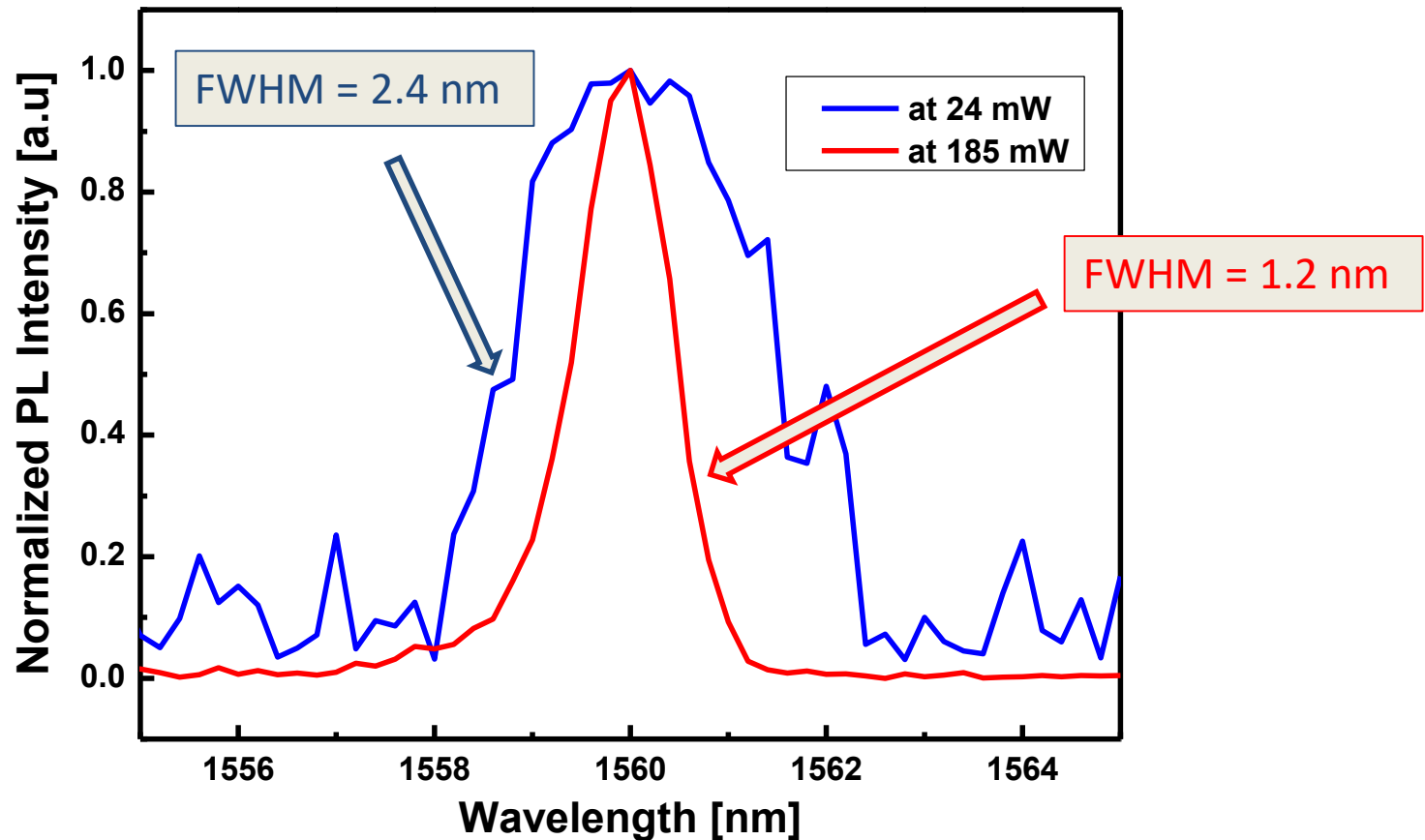
SEM micrograph of the  $\text{Er}^{3+}$  doped 1D dielectric microcavity cross section. The bright and dark region corresponds to  $\text{TiO}_2$  and  $\text{SiO}_2$  layers, respectively. The substrate is located on the bottom of the images and air on the top.



The first order stop band ranges from 1300 nm to 1850 nm. The first order cavity resonance corresponds to the sharp maximum centered at **1559.2 nm**. Transmission spectra representing third order stop band in the visible region between 500 nm to 560 nm with third order cavity resonance at **536 nm**.

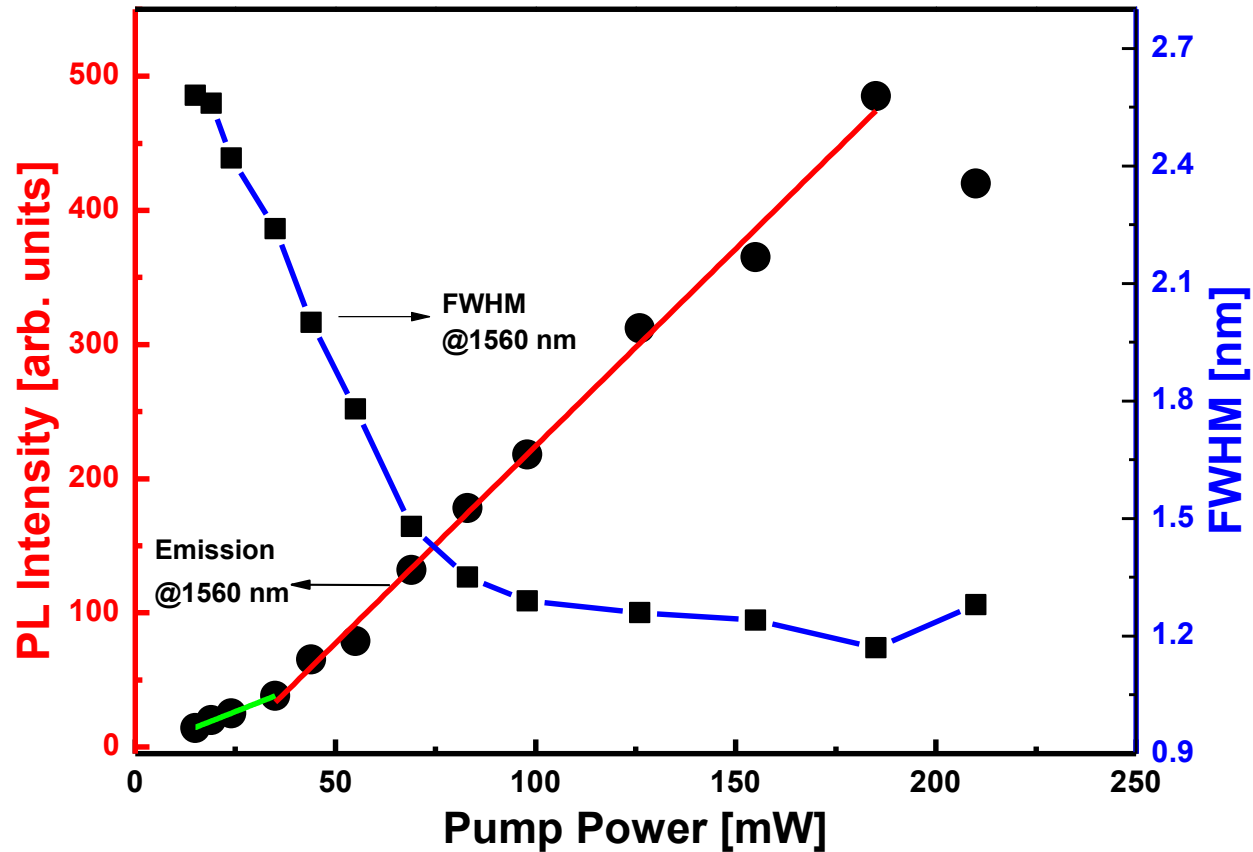


## $^4I_{13/2} \rightarrow ^4I_{15/2}$ photoluminescence spectrum



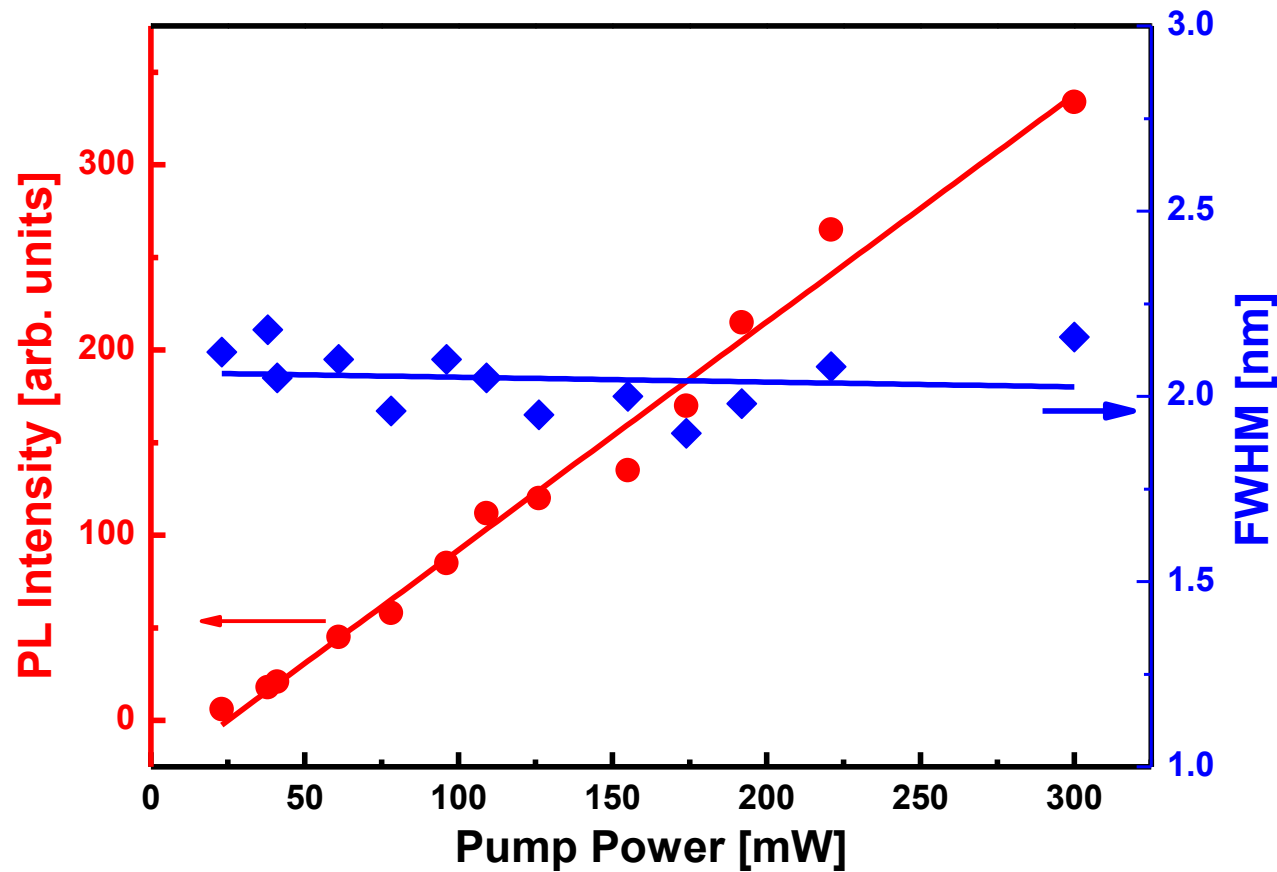
$^4I_{13/2} \rightarrow ^4I_{15/2}$  photoluminescence spectrum of the cavity activated by  $\text{Er}^{3+}$  ions in 1D dielectric microcavity. The emission is recorded at 0 degree from the normal on the samples upon excitation at 514.5 nm at the input power of 185 mW (red line) and 24 mW (blue line). 30 degree of excitation angle for both the measurements.

**Peak intensity and FWHM vs Pump Power**  
**Exciting at 514.5 nm / 30°**



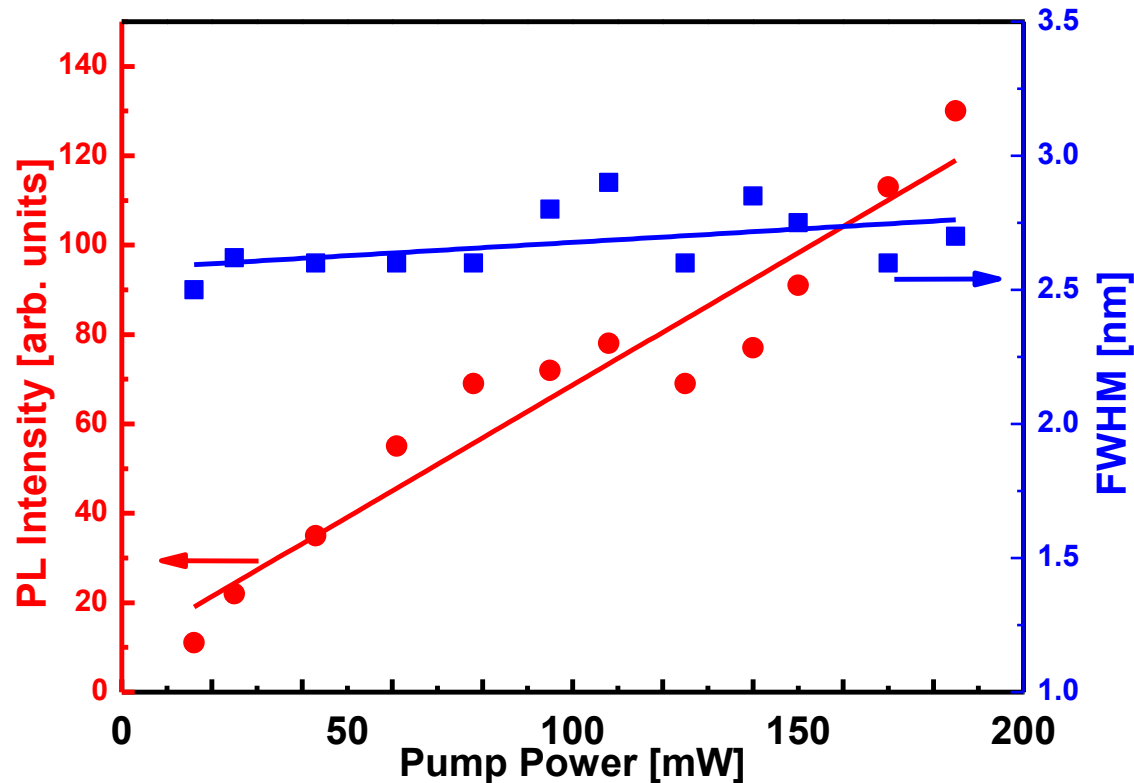
$^4I_{13/2} \rightarrow ^4I_{15/2}$  photoluminescence peak intensity and FWHM (blue line) at 1560 nm as a function of 514.5 nm pump power with 0 degree of detection angle and 30 degree of excitation angle. Red and green line are the results of linear fit while the blue line is a guide for the eyes.

**Peak intensity and FWHM vs Pump Power**  
**Exciting at 514.5 nm /  $\neq 30^\circ$**



$^4I_{13/2} \rightarrow ^4I_{15/2}$  photoluminescence peak intensity and FWHM (blue line) at 1560 nm as a function of 514.5 nm pump power with 0 degree of detection angle and 45 degree of excitation angle. Red and blue line are the results of linear fit.

**Peak intensity and FWHM vs Pump Power**  
**Exciting at 980 nm / 30°**



$^4\text{I}_{13/2} \rightarrow ^4\text{I}_{15/2}$  photoluminescence **peak intensity (red)** and **FWHM (blue)** at 1560 nm as a function of 980 nm pump power with 0 degree of detection angle and 30 degree of excitation angle. The blue and red lines are the results of linear fit.

## Conclusions

- ❖ Photonic crystals that exhibit specific morphologic, structural, and optical properties allow to develop interesting new physical concepts, as well as novel photonic devices based on the control of the light.
- ❖ The cavity is designed to present a cavity resonance at 1560 nm at 0° of detection that correspond to the  $^4I_{13/2} \rightarrow ^4I_{15/2}$   $\text{Er}^{3+}$  ions emission and a third order resonance placed at around 514 nm with 30° of incidence from the normal of the sample that is used to pump the sample with an Ar+ laser line.
- ❖ The behavior of the emission intensity at emission wavelength of 1560 nm and FWHM as a function of different 514.5 nm excitation powers, with a detection angle of 0° and an excitation angle of 30°, is nonlinear. Simultaneously there is a narrowing of the FWHM from 2.5 nm at low pump power to approximately 1 nm, which is limited by a spectral resolution of our experimental set up with a threshold power of 30 mW.

# Acknowledgement

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